

SALIX

Wet System

SALIX – Wet Scrubbing of Waste Gases from Wet Bench Applications

The wet scrubber SALIX has been designed for new requirements in wet clean technologies in the semiconductor industry, with focus on chemical wet clean processes with large gas flow rates. The system reliably treats isopropyl alcohol (IPA), ammonia and hydrogen fluoride from waste gases from single wafer clean tools.

Efficient treatment of water-soluble gaseous compounds such as

- › Alcohols
- › Solvents (water-soluble)
- › Acids
- › Ammonia

Removal of particulate matters from the waste gas flow

- › Salts
- › Droplets

Status

- › Development started in 2012
- › More than 1,500 systems in the field

Application

- › Single wafer wet clean

Goals

- › Maintenance cycles for > 1 year

Basic Features

- › Smaller and less complex exhaust piping
- › Smaller load to central treatment systems
- › Reduced loss of clean room air
- › Smaller footprint
- › Higher flexibility for process changes
- › High pressure stability in process chamber
- › Low emission concentrations
- › Elimination of salt particle formation from acids and bases



High Flow Solution **SALIX**
Wet scrubber with highest DRE and total capacity



Compact Solution **SALIX MINI**
Wet scrubber with lowest footprint

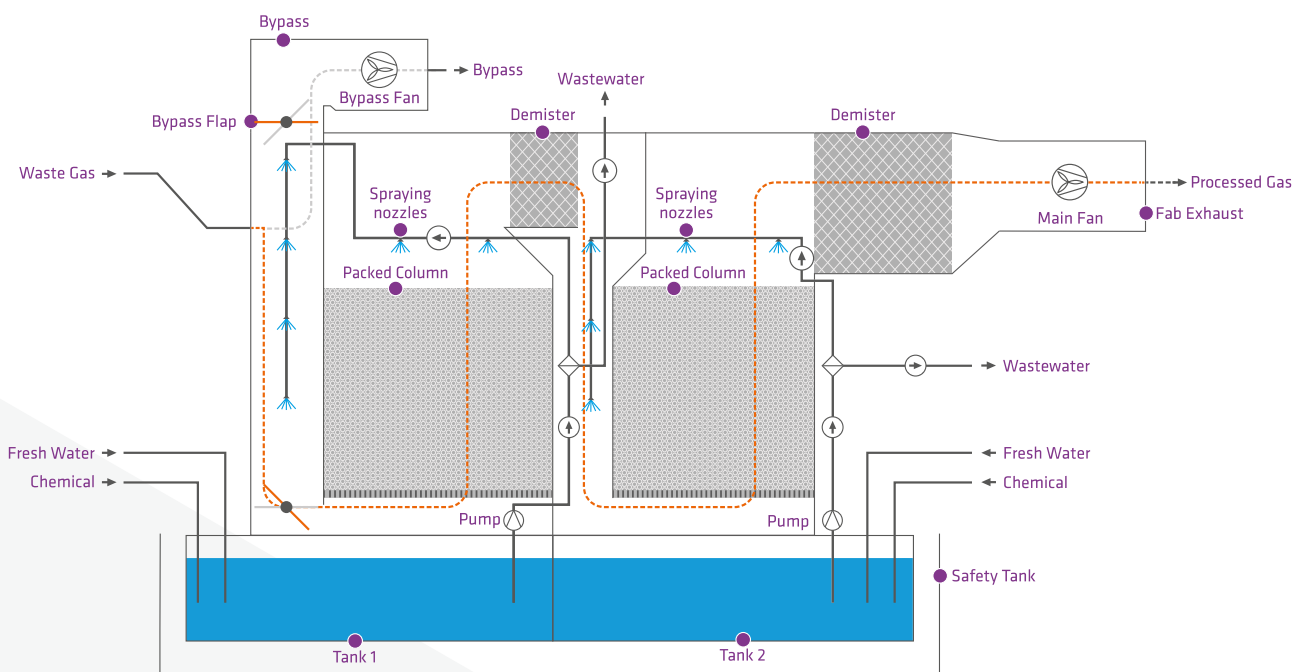
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Technical Data

	SALIX	SALIX MINI
Dimensions (W x D x H)	3207 mm x 1250 mm x 2493 mm	1500 mm x 1530 mm x 1700 mm
Max. Inert Gas Flow	5500 m ³ /h	4000 m ³ /h
Max. Gas Entry	flexible	flexible
Gas Outlet	DN 300 - 450	DN 250 - 450

System Description



System Description for High Flow Solution **SALIX**

- › Up to 12 waste gas inlets into scrubber stage 1
- › Pre-cleaning of waste gases right behind the inlets
- › Mixed waste gases pass through packed column (counter flow principle)
→ cleaning by combination of nozzles and packed material (increased surface area)
- › Demister removes droplets in the gas flow to scrubber stage 2 and prevents carry-over of scrubbing liquid
- › Demister after stage 2 avoids carry-over of droplets in the exhaust system
- › Optional bypass secures continuation of process in case of system maintenance or unscheduled events